Docket No. 5312/CMI/WCVD/RKK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application Commissioner of Patents and Trademarks Washington, D.C. 20231

Re:

Inventor(s): THOMAS P.H.F. WENDLING

Title:

APPARATUS AND METHOD FOR EVENLY FLOWING PROCESSING GAS ONTO A SEMICONDUCTOR WAFER

Transmitted herewith is the patent application identified above, including:

X Specification, claims and abstract, totaling 11 pages.

X Drawings totaling 2 pages, X Formal

Executed Declaration and Power of Attorney.

Assignment of the invention to Applied Materials, Inc.

Assignment Recordation Cover Sheet

Information Disclosure Statement and Form 1449 along with copies 19 references recited therin

FEE CALCUI	LATION				
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	14	-20=	0	X\$18.00	\$000.00
Independent Claims	3	-3=	0	X\$84.00	\$000.00
Basic Filing Fee \$710.00					\$740.00
TOTAL FEES					\$740.00

- XXThe Commissioner is hereby authorized to charge \$740.00 to Deposit Account No. 50-1074.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to XXDeposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
- XXPlease address all future correspondence to:

PATENT COUNSEL APPLIED MATERIALS, INC. **Legal Affairs Department** P.O. BOX 450A Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Robert W. Mulcahy Pecific Registration No. 25,436

Respectfully submitted.